

IN THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application.

1. (Currently Amended) A fabrication system comprising:

a load chamber;

a transport chamber connected with said load chamber;

a plurality of film formation chambers connected with said transport chamber; and

an installation chamber connected with each of said film formation chambers;

wherein each of said plurality of film formation chambers comprises:

an aligner for allowing positions of a mask and a substrate to be in registry with each other;

~~a substrate holder~~ a frame having a metal plate which is perpendicular to the substrate;

a plurality of evaporation source holders; and

a moving mechanism for moving said evaporation source holders;

wherein each of said evaporation source holders have containers, said containers being arranged in a longitudinal direction of each of said evaporation source holders, in each of said containers an evaporation material is contained and a heater for heating said containers;

wherein said installation chamber comprises:

a heater for heating said containers previously; and

a transport for transporting said containers into said evaporation source holders in said film formation chamber;

wherein each of said plurality of film formation chambers is connected with a first vacuum exhaust treatment chamber for allowing an inside of each of said film formation chambers to be in a vacuum state; and

wherein said installation chamber is connected with a second vacuum exhaust treatment chamber for allowing an inside of said installation chamber to be in a vacuum state.

2. (Currently Amended) The vapor deposition system according to claim 1, wherein said ~~substrate holding device~~ frame overlapped a terminal region, a cut region, or an end portion of the substrate with a mask being sandwiched therebetween.

3. (Currently Amended) The fabrication system according to claim 1, wherein said ~~substrate holding device~~ frame and said mask are bonded or welded with each other.

4. (Previously Presented) The fabrication system according to claim 1, wherein said moving mechanism for moving said evaporation source holders has a mechanism moving said evaporation source holders in an X-axis direction at a given pitch and, further, a Y-axis direction at another given pitch.

5. (Original) The fabrication system according to claim 1, wherein said containers are arranged at equal intervals in each of the evaporation source holder.

6. (Original) The fabrication system according to claim 1, wherein the evaporation sources holders is rectangular.

7-18. (Canceled)

19. (Currently Amended) A fabrication system comprising:

a load chamber;

a transport chamber connected with said load chamber;

a plurality of film formation chambers connected with said transport chamber; and

an installation chamber connected with each of said film formation chambers;

wherein each of said plurality of film formation chambers comprises:

a CCD camera and a stopper for allowing positions of a mask and a substrate to be in registry with each other;

a frame having a metal plate which is perpendicular to the substrate;

a plurality of evaporation source holders; and

a stage for moving said evaporation source holders;

wherein said each of evaporation source holders have containers, said containers being arranged in a longitudinal direction of each of said evaporation source holders, in each of said containers an evaporation material is contained; and a heater for heating said containers;

wherein said installation chamber comprises:

a heater for heating said containers previously; and

a transporting robot for transporting said containers into said evaporation source holders in said film formation chamber;

wherein each of said plurality of film formation chambers is connected with a first vacuum exhaust treatment chamber for allowing an inside of each of said film formation chambers to be in a vacuum state; and

wherein said installation chamber is connected with a second vacuum exhaust treatment chamber for allowing an inside of said installation chamber to be in a vacuum state.

20. (Original) The vapor deposition system according to claim 19, wherein said frame overlapped a terminal region, a cut region, or an end portion of the substrate with a mask being sandwiched therebetween.

21. (Original) The fabrication system according to claim 19, wherein said frame and said mask are bonded or welded with each other.

22. (Original) The fabrication system according to claim 19, wherein said stage has a mechanism moving said evaporation source holders in an X-axis direction at a given pitch and, further, a Y-axis direction at another given pitch.

23. (Original) The fabrication system according to claim 19, wherein said containers are arranged at equal intervals in each of said evaporation source holders.

24. (Currently Amended) The fabrication system according to claim 19, wherein the ~~rectangular~~ evaporation source holders are rectangular.

25-28. (Canceled)

29. (Previously Presented) The fabrication system according to claim 1, wherein said aligner has at least a CCD camera.

30-33. (Canceled)

34. (New) The vapor deposition system according to claim 1, wherein said frame is provided between said source holder and said mask.

35. (New) The vapor deposition system according to claim 19, wherein said frame is provided between said source holder and said mask.

36. (New) The vapor deposition system according to claim 1, wherein said source holder passes under said frame and said mask.

37. (New) The vapor deposition system according to claim 19, wherein said source holder passes under said frame and said mask.